TECHNICAL DATA

LONGLITE[®] DRY FILM PHOTO RESIST

FF-9075S

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SUMMARY

LONGLITE[®] Dry Film Photo Resist FF-9075S is negative working and aqueous photo polymer. FF-9075S is suitable for the applications of acidic etching, tenting, copper / tin plating, and copper / tin-lead plating in PCB manufacturing.

FEATURES

- 1. Excellent adhesion and conformation capability.
- 2. Excellent chemical resistance for plating application.
- 3. Excellent resolution characteristics.
- 4. Wilder latitude for exposure.
- 5. Wider margin in development.
- 6. High tenting reliability.
- 7. Low sludge in development bath.
- 8. Less contamination to plating bath.

SPECIFICATION

 $\begin{array}{ll} FF-9075S & 75 \mu m \pm 2 \mu m \\ Standard width interval: & 0.125 inch. \\ Standard length: & 500 \ ft \ / \ roll \end{array}$

STORAGE AND SAFTY HANDLING

- Store horizontally in a cool and dry warehouse with temperature $5 \sim 20^{\circ}$ C and RH $50 \pm 10^{\circ}$.
- Safe to use under UV-cut yellow fluorescent lamps. When not using, seal by black sheet such as its original black plastic packing sheet, and lay down dry film rolls horizontally for storage.
- Lamination will cause vapor, use in room with adequate ventilation.
- Avoid contacting the resist layer of dry film with skin directly which may cause irritation. Wash with soap and water thoroughly after handling. If persistent irritation occurs, consult a physician.

 ϖ LONGLITE[®] is the registered trade mark owned by CHANG CHUN PLASTICS CO., LTD.

SENSITIVITY AT VARIOUS EXPOSURE ENERGIES

| Grade | | FF-9075S | |
|---------------------------------------|-----|--------------------|--|
| Developing time | | 96 sec (B.P 48sec) | |
| Exposure Energy mJ/cm ² | 20 | 6 | |
| | 30 | 7 | |
| | 40 | 8 | |
| | 50 | 9 | |
| | 60 | 9.5 | |
| | 70 | 10 | |
| | 80 | 10.5 | |
| | 90 | 11 | |
| | 100 | 11.5 | |

*Data for reference

* Exposure was given by placing Stouffer 21 step guide directly in contact with DFR, and counted the steps still remaining after development.



RESOLUTION AT VARIOUS EXPOSURE ENERGIES

| Grade | | FF-9075S |
|---------------------------------------|-----|------------|
| | | Space (µm) |
| | 20 | 60 |
| Exposure Energy mJ/cm ² | 30 | 60 |
| | 40 | 60 |
| | 50 | 80 |
| | 60 | 80 |
| | 70 | 100 |
| | 80 | 125 |
| | 90 | 150 |
| | 100 | 150 |

*Data for reference

***** Test pattern: CCP Pattern 1 (L/S = 1/2), from 20 to 200µm 5 "L" shape lines each.



ADHESION AT VARIOUS EXPOSURE ENERGIES

| Grade | | FF-9075S |
|---------------------------------------|-----|-----------|
| | | Line (µm) |
| | 20 | 125 |
| Exposure Energy mJ/cm ² | 30 | 100 |
| | 40 | 80 |
| | 50 | 60 |
| | 60 | 60 |
| | 70 | 60 |
| | 80 | 50 |
| | 90 | 50 |
| | 100 | 50 |

*Data for reference

***** Test pattern: CCP Pattern 1 (L/S = 2/1), from 20 to 200 µm 5 "L" 1shape lines each.



VARIATION IN RESIST WIDTH AT VARIOUS EXPOSURE ENERGIES

| Grade | | FF-9075S | |
|---------------------------------------|-----|----------------------|--|
| | | Width Variation (µm) | |
| Exposure Energy mJ/cm ² | 20 | -5 | |
| | 30 | -2 | |
| | 40 | 0 | |
| | 50 | 2 | |
| | 60 | 5 | |
| | 70 | 5 | |
| | 80 | 10 | |
| | 90 | 15 | |
| | 100 | 18 | |

*Data for reference

X Measuring resist width variation from test pattern after development. Test pattern L/S= 100 / 200μm.



STRIPPING

| | | Stripping time (sec) | | | Stripped piece | | |
|-------------|-------------------|----------------------|------|------|----------------|----|----|
| Stripper | NaOH | 2% | 3% | 4% | 2% | 3% | 4% |
| Temperature | 50 ⁰ C | 157" | 150" | 144" | MS | MS | L |
| remperature | 55°C | 151" | 141" | 127" | MS | М | ML |
| | 60 ⁰ C | 141" | 128" | 120" | М | ML | ML |

*Data for reference

X Tested by dipping.

X Stripped piece size:

LL :sheet

L : about 3 cm

ML : about 2 cm.

M : about 1 cm.

MS : about 0.5 cm S : about 0.3 cm

TENTING

| strength (g) | 590.1 |
|--------------|-------|
| Time(sec) | 4.37 |

Remark:

- a. Data for reference
- b. Step: 8 Step
- c. Gauge: ϕ 2mm.
- d. Speed: 10mm/min.
- e. Board: \$\$\phi6mm\$, thickness 1.6mm\$.

RECOMMENDED OPERATION CONDITIONS

 Surface pretreatment: Method Inner : Chemical brush, Pumice brush Outer : Buffering brush + Pumice brush Water break test: At least 15~30 sec (vertically)
Don't dry board with hot air directly while the board surface still has water on it.
Recommended surface roughness: R_a=0.2~0.4 µm , R_z=1.5~2.5 µm

Lamination: 110±10℃ Roll temperature: $3\sim5$ kg/cm² Pressure: 1.0~3.0 m/min Speed: 55~65℃ Seal bar temperature: Seal bar pressure: $2\sim5$ kg/cm² 1.5~2 sec Seal time: 40~60°C Board temperature before lamination: Board temperature after lamination: 45~55℃ 15 min~2days (23±2°C, 50±10% RH) Holding time^①

• The temperature and pressure of the roll should be adjusted in accordance with the structure of the particular laminator.

- To shade the panels when leaving them for more than six hours under a UV-free yellow light.
- <u>Exposure</u>:

| Energy: | 30~60 mj/cm ² |
|---------------------------|---|
| Step: | 7~9 step of Stouffer Sensitivity Tablet 21 step |
| Holding time [®] | 15 min~2days. (23±2°C, 50±10% RH) |

► Holding time① + Holding time② < 4 days

• Development:

| Developer: | 0.8~1.2 wt% Na ₂ CO ₃ |
|--------------|---|
| Temperature: | 26~30℃ |
| Pressure: | $1.2 \sim 2.0 \text{ kg/cm}^2$ |
| Break point: | 1/2~2/3 |

► Water rinsing after development is recommended to be done at 15-25°C and a spray pressure of 1.2-2.0 kg/cm²

• Keep the pH of rinsing water in the first tank below 8.5

• The loading content for resist should be adjusted to 6g/l or less.

| • | Etching: | |
|---|----------|------------------------------------|
| | Туре | Acidic |
| | Etchant: | Cupric chloride or Ferric chloride |

• <u>Stripping</u>

| Stripper: | 2.5~3.0% NaOH or KOH |
|----------------|--------------------------------|
| Temperature: | 50±5℃ |
| Pressure: | $1.0 \sim 3.0 \text{ kg/cm}^2$ |
| Lifting point: | 1/2~2/3 |

► The loading content of resist should be adjusted to 20g/l or less.

▶ Water rinsing after stripping is recommended to be done at spray pressure of 1.0kg/cm² or more.